



**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q64059

Shigeo ISHIKAWA

Appln. No.: 09/832,093

Group Art Unit: 2823

Confirmation No.: 8684

Examiner: Khiem D. Nguyen

Filed: April 11, 2001

For: FILM FORMING METHOD IN WHICH FLOW RATE IS SWITCHED

**STATEMENT UNDER 37 C.F.R. § 1.97(e)**


Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The undersigned hereby states, upon information and belief:

That each item of information contained in the Information Disclosure Statement filed concurrently herewith was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of said Information Disclosure Statement.

Respectfully submitted,

  
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WASHINGTON OFFICE

**23373**

CUSTOMER NUMBER

Date: July 29, 2003